

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF

Inventor(s): HASEGAWA et al.

Filed: Herewith

Title: METHOD OF PURGING CVD APPARATUS AND METHOD FOR JUDGING
MAINTENANCE OF TIMES OF SEMICONDUCTOR PRODUCTION APPARATUS

December 19, 2001

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents
Washington, D.C. 20231

Sir:

Please amend this application as follows:

IN THE SPECIFICATION:

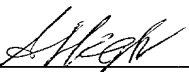
At the top of the first page, just under the title, insert:

1. ☒--This is a ☐ Continuation-In-Part ☒ Divisional
☐ Continuation ☐ Substitute Application (MPEP 201.09) of
1(a) ☒ National Application No. 09/651,255 filed August 30, 2000.
1(b) ☐ International Application No. PCT/___/
filed ___ which designated the U.S.--
2. ☐--This application claims the benefit of U.S. Provisional Application No.
60/___, filed ___.—

IN THE CLAIMS:

Please cancel claims 1 and 8-14 without prejudice.

Respectfully submitted,
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Intellectual Property Group

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